



1765
[10191/3964]

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s) : Franz LAERMER et al.
Serial No. : 10/530,612
Filed : December 30, 2005
For : **PLASMA SYSTEM AND METHOD FOR
ANISOTROPICALLY ETCHING STRUCTURES
INTO A SUBSTRATE**

Art Unit : 1765
Examiner : Maki A. Angadi
Confirmation No. : 6739

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Mail Stop AF, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on

Date: July 30, 2007

Reg. No. 31,792

Signature: _____

Richard M. Rosati

AMENDMENT

SIR:

In response to an April 5, 2007 Office Action in the above-identified application, please amend, without prejudice, the above-captioned application as follows. Applicants request a **one-month extension of time** to respond to the Office Action (extended periods expires on August 5, 2007), and the Office is authorized to charge the one-month extension fee of **\$120** to **Kenyon & Kenyon LLP's** Deposit Account No. **11-0600**.

Amendments to the Claims are reflected in the **Listing of Claims**, which begins on page 2 of this paper.

Remarks begin on page 6 of this paper.

08/02/2007 SSESHE1 00000010 110600 10530612

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